

## ABSTRACT OF THE DISCLOSURE

A method for placement of an object such as a substrate or a mask on a table, said method including:

a first placement step in which the object is placed on a first position on the table;

a measuring step in which a displacement between the first position of the object and the required position of the object is determined;

a removing step in which the object is released and removed from the table;

a moving step in which the object and the table are moved relatively to each other by substantially the said displacement, in a direction substantially parallel to the surface of the table; and

a second placement step in which the object is placed at the required position on the table.

## ABSTRACT:

“Object positioning method for a lithographic projection apparatus”

A method for placement of a object 1 such as a substrate or a mask on a table 5,  
5 said method comprises the following steps:

a first placement step in which the object 1 is placed on a first position on the  
table 5;

a measuring step in which a displacement between the first position of the object  
1 and the required position of the object 1 is determined;

10 a removing step in which the object 1 is released and removed from the table 5;

a moving step in which the object 1 and the table 5 are moved relatively to each  
other by substantially the said displacement, in a direction substantially parallel to the surface  
13 of the table 5; and

15 a second placement step in which the object 1 is placed at the required position on  
the table 5.

Fig. 5